

ABSTRACT

MEMS micromotor and timepiece equipped with this micromotor

5 The invention proposes a MEMS micromotor produced in a plate
made of crystalline or amorphous material, in particular based on silicon,
which comprises a lower layer forming a substrate, and an upper layer in
which at least one actuator and a rotor is etched, the actuator driving the
rotor in rotation about a shaft (64), characterised in that the shaft (64) is
10 connected to the plate, in that the shaft (64) extends axially through a hole
of the plate, and in that the shaft (64) is clamped in the hole and centred in
the hole by means of elastic fixing structures which are produced by etching
in the substrate and which are arranged on the circumference of the hole.

15 Figure 5.